

Advances in Statistical Compact Modeling

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Overview

- Statistical Compact Modeling and use model
- Method is available as GUI based MunEDA WiCkeD App "Statistical Fit"
- Data normalization for fitting
- **★** Excluding mismatch effects by calculation from PCM measurements
- Helpful input data consistency checks
- Validation of results



Task and implementation idea

Target User Group

CAD Modeling & Characterization engineers

Task

- Improve consistency of statistical spice models according to variations and correlations in order to ...
- Improve the variation of analog device behavior in statistical (Monte Carlo) simulations

Implementation idea

- Introducing correlations with statistical spice model card parameters
- The standard deviation is taken from PCM specification
- The correlations between PCMs can be extracted from PCM measurements



General use model

PCM specification source of the PCM standard deviation

PCM spice simulation
PCM testbench with initial
statistical models

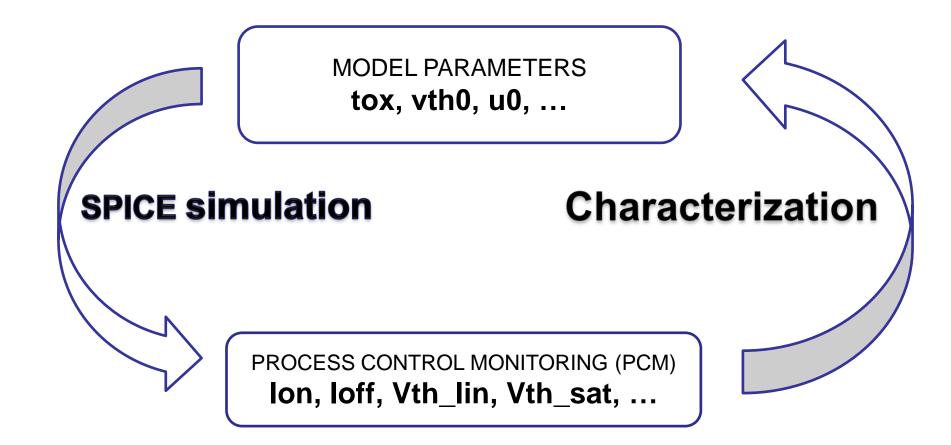
PCM data sets
(measurements)
source of the
PCM correlation

ElaboratingWiCkeD "Statistical Fit"

Improved device statistics models



Relation between model parameters and PCM re-simulation





Correlations between model parameters (vth0, u0, tox, ...) are necessary to reproduce correct variance and correlation in process MC for analog circuits



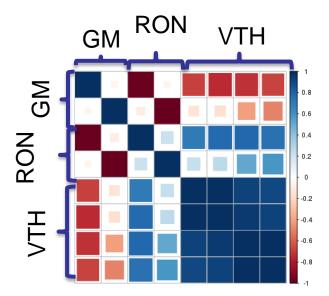
Why is the correlation between PCMs so important for analog design?

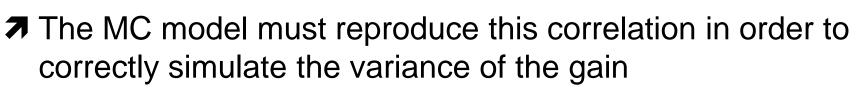
Common source single stage amplifier

7 Low frequency gain: A_v=G_m⋅R_{on}

7 There is strong negative correlation between

G_m and R_{on}:

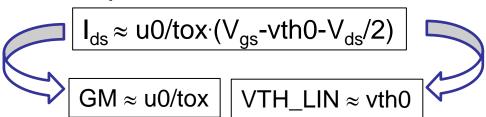




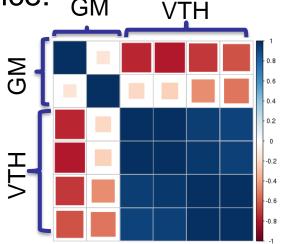


Typical problem with modeling of the correlation of PCMs

- **★** Three typical model parameters for process MC:
 - tox oxide thickness
 - u0 mobility
 - vth0 threshold voltage



- **尽** Consider two PCMs from the same device:
 - GM maximum gm
 - VTH_LIN extrapolated Vth
- **★** The variance of Gm:
 - $\approx 60\%$ dependence on u0
 - $\approx 40\%$ dependence on tox
- **→** The variance of VTH_LIN:
 - ≈ 100% dependence on vth0



tox, u0 and vth0 must be correlated to see a correlation of GM and VTH_LIN in simulation



Linear dependence of PCM variation on Model parameter variations

Assumption of a linear dependency between PCM and model parameters

$$\Delta P = S \cdot \Delta M$$

- \triangleright $\triangle P$ variation of PCM
- **尽** S − sensitivity of PCMs w.r.t. model parameters M (by simulation)
- \rightarrow ΔM variation of model parameters

$$cov(P) = S \cdot cov(M) \cdot S^T$$

Least-Squares fit:

$$\min_{X} ||cov(P) - S \cdot X \cdot S^{T}||^{2}$$

$$\uparrow \qquad \qquad \uparrow \qquad \text{simulated} \qquad \qquad \uparrow \qquad \qquad \uparrow$$

$$\uparrow \qquad \qquad \uparrow \qquad \qquad \downarrow \qquad \qquad \uparrow \qquad \qquad \downarrow$$



Covariance matrix of PCM

- **★** The variances of target PCMs are defined by specification:
 - $-\sigma(P)$ are defined from technology, e.g. (USL-LSL)/9
- **★** The correlation of PCMs are measured by the FAB:
 - corr(P) are calculated from wafer
- **尽** Covariance matrix of PCM are constructed from variances and correlations of PCMs:

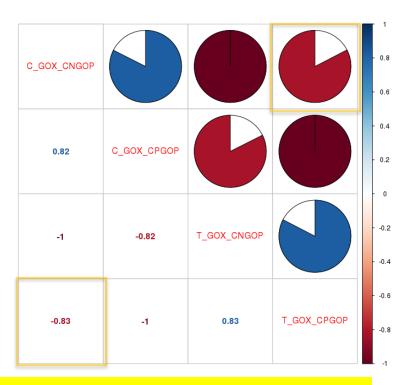
$$cov(P) = \sigma(P) \cdot corr(P) \cdot \sigma(P)$$



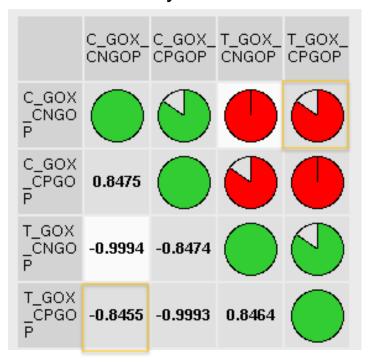
Capacitor example

- **◄** E.g. two different types of capacitors:
 - Modelled with two parameters and one correlation factor
 - toxntoxpcc_toxn_toxp

Correlation matrix of PCM measurements



Simulation by Monte-Carlo



cc(T_GOX_CPGOP,C_GOX_CNGOP)=-0.83

cc(T_GOX_CPGOP,C_GOX_CNGOP)=-0.85

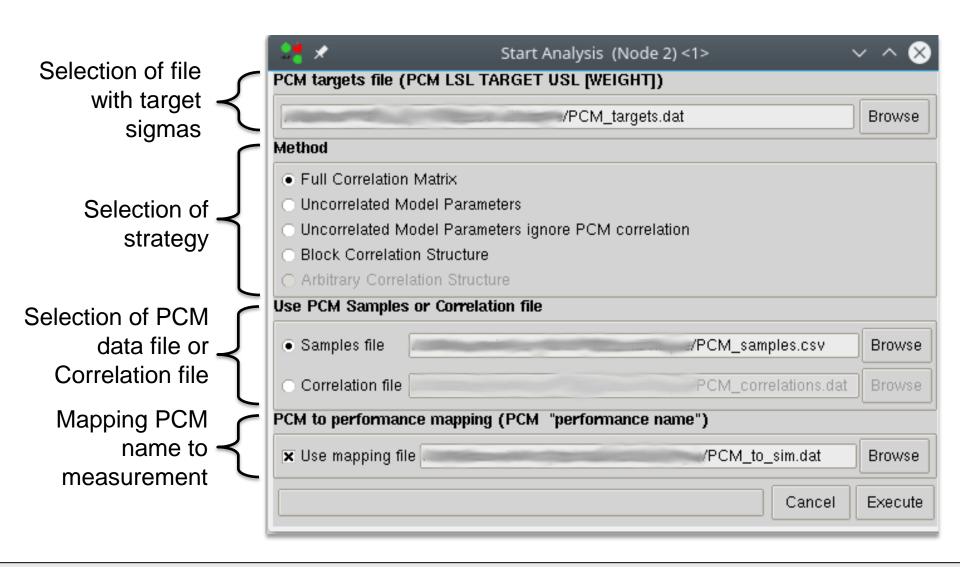


MunEDA WiCkeD App "Statistical Fit"

- GUI tool to create Statistical Models considering PCM correlations for analog transistor behavior that reproduce long-term process variation
- MunEDA WiCkeD is applied to the PCM netlists
 - Simulation setup with initial variation model of spice models
 - Selection of statistical model card parameters to consider
- Additional inputs of "Statistical Fit"
 - PCM measurements (data sets) for correlations target
 - PCM specification to determine the standard deviation of the statistical model card parameters as well
- Results of "Statistical Fit"
 - Set of model parameter sigmas (global MC parameters) and
 - correlations between them
- Benefit: More realistic sigmas / correlations of MC parameters
 - Safer verification
 - Less pessimism in design → better utilization of process technology



Screenshot of the WiCkeD App "Statistical Fit"





Nonlinear PCMs with respect to the statistical model parameters

Assumption of a linear dependency between PCM and model parameters

$$\Delta P = S \cdot \Delta M$$

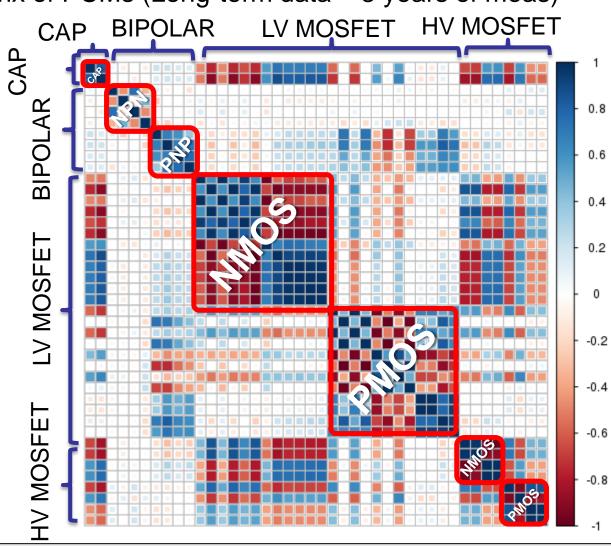
- ΔP variation of PCM
 - S sensitivity of PCMs w.r.t. model parameters M (by simulation)
- ΔM variation of model parameters
- **尽** Sample PCMs are not linear; transform them to alternative:
 - COX measurements of capacitance ⇒ TOX oxide thickness
 - RON measurements of on-resistance ⇒ GON on-conductance
 - ILEAK leakage current ⇒ log(ILEAK) logarithm of ILEAK
- In order to include second order nonlinearities into the dependence of PCMs on parameter variation, consider, "quadratic BPV" *
 - * I. Stevanovic, C.C.McAndrew, "Quadratic Backward Propagation of Variance for Nonlinear Statistical Circuit Modeling", IEEE on CAD, V.28,No.9, 2009



Sample structure of correlation matrix of PCMs (Measurement)

Typical correlation matrix of PCMs (Long-term data – 3 years of meas)

- **7** DEVICES
- **7** CAPACITOR
 - Different types
- **7** BIPOLAR
 - NPN
 - PNP
- **↗** Low Voltage MOSFET
 - NMOS (diff geom)
 - PMOS (diff geom)
- → High Voltage MOSFET
 - NMOS (diff geom)
 - PMOS (diff geom)





Strategies for Statistical Compact Modeling

Method	Purpose	Matrix of PCMs		Matrix of Model Parameters	
Full Correlation Matrix	Mathematical approach without physical distinguishes of model parameters	Full Covariance	1 4 4 4 4 4 4 4 4 4 4 4 4 4 4 4 4 4 4 4	Full Covariance	
Uncorrelated Model Parameters	Pay attention on correlation of PCMs, but produce uncorrelated model parameters matrix	Full Covariance		Only diagonal elements	0
Uncorrelated Model Parameters ignore PCM correlation	Unknown correlation between PCMs, preliminary estimation of model parameters' sigmas	Only diagonal elements	?	Only diagonal elements	0
Block Correlation Structure	Known correlation structure of model parameters, take into account correlation between PCMs	Full Covariance	1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1 1	Block-wise model parameters	0
Arbitrary Correlation Structure	Know correlation structure of model parameters, but not block wise	Full Covariance		Arbitrary structure	0

17



Normalization for least square fit

- **7** PCMs have different orders of magnitude ($k\Omega$, μ A, ...). Normalization needed to avoid large values dominating.
- **7** PCMs have different relative variation σ/μ . Normalization needed to reduce weights of PCMs with $\sigma/|\mu| \ll 1$

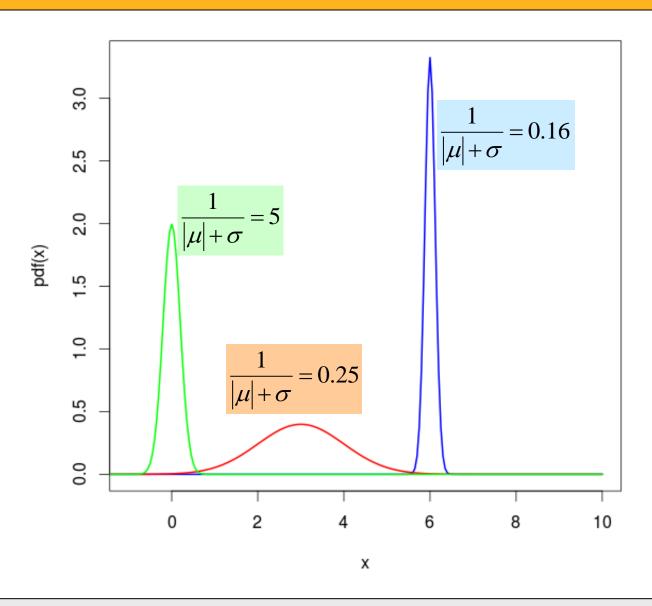
Normalization factor for every PCM:
$$\frac{1}{\sigma} \cdot \frac{\sqrt[\sigma]{|\mu|}}{1 + \sqrt[\sigma]{|\mu|}} = \frac{1}{|\mu| + \sigma}$$

– i.e. instead of minimizing the difference in σ^2 , we minimize the difference in $\sigma^2/(|\mu|+\sigma)^2$.

$$\min_{X} || N \cdot (\text{cov}(P) - S \cdot X \cdot S^T) \cdot N ||^2 \text{ with } N = \text{diag}(1/(|\mu| + \sigma))$$



Weight comparison of three example PCM



- PCM with smaller σ/μ are weighted less
- Works for μ =0
- Works for σ =0



Removing of mismatch effects from the target PCM covariance matrix

- The PCM measurements contain both process and mismatch effects.

 But, the correlation shall be just generated for the process variation.

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 The PCM measurements co
- Mismatch can be removed via the covariance matrix cov(P, process) = cov(P, measured) − cov(P, mismatch)
- The mismatch covariance matrix is determined assuming a linear dependency between PCM and mismatch parameters

$$\Delta P = S_{mm} \cdot \Delta MM$$

 ΔP variation of PCMs

S_{mm} sensitivity of PCMs w.r.t. mismatch parameters (simulation)

Δ**MM** variation of mismatch spice model parameters

using

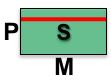
$$cov(P,mismatch) = S_{mm} \cdot cov(mm) \cdot S_{mm}^{T}$$

7 cov(mm) is the covariance matrix of the mismatch model card parameters that are mm ~ N(0,1²) distributed. So, cov(mm) is typically an identity matrix.

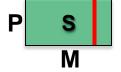


Input data consistency checks and improved data cleaning

- 1. Detection of PCMs with a low/no sensitivity towards the process parameters
 - There is no process parameter that can be used to model the variation of that PCMs
 - Case can be detected in the sensitivity matrix as (close to) zero row(s)



- → User to add the missing process parameters
- → To continue, those PCMs are excluded from further calculations
- 2. Detection of process parameters with a low/no sensitivity towards the PCMs
 - Without a sensitivity to PCMs, the statistics of those process parameters cannot be determined
 - Case can be detected in the sensitivity matrix as (close to) zero column(s)

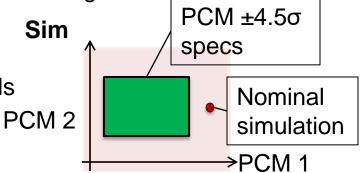


- → User to pick the correct process parameter set
- → To continue, such process parameters are excluded from further calculations

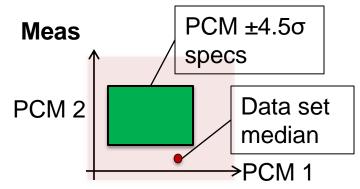


Input data consistency checks and improved data cleaning

- 3. Detection of PCMs nominal simulation outside of the PCM specification
 - The nominal PCM simulation does not fit to the PCM targets
 - Can be detected comparing the PCM nominal simulation with the PCM targets
 - → Adjust the nominal simulation in the spice models
 - → To continue, those PCMs are excluded from the calculations



- Detection of PCM measurement median outside of the PCM specification
 - The PCM median of the measurements does not fit to the PCM specification
 - Can be detected comparing the median with the PCM targets
 - → Verify that the preprocessing steps of the PCM measurements are correct
 - → Correct the PCM targets and specifications





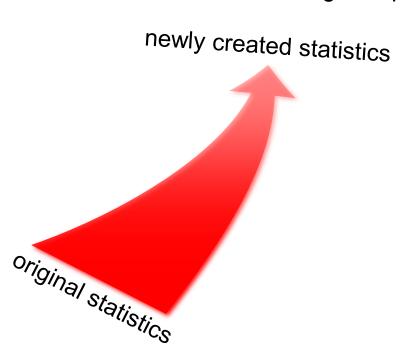
Input data consistency checks and improved data cleaning

- 5. Removing outliers from PCM measurements
 - Values outside of median ±5.5σ are considered as outliers
 - PCM data sets have many missing values
 - Do not remove complete data sets → would reduce the number of data sets significantly
 - · Instead mark outliers as missing value
 - → Simplifies preprocessing of PCM measurement data
- 6. After determining the new statistics: identify almost not varying process model parameters
 - The calculated standard deviation of the process parameter will be very small
 - → Those model card parameter do not need to be varied in the spice models



Monte Carlo based validation of determined statistics

- Allows comparisons of new model statistics to target and original statistics
- Three PCM covariance matrixes to compare
 - PCM target covariance
 - Covariance based on newly created statistics (result of Monte Carlo analysis)
 - Covariance based on original spice models (result of Monte Carlo analysis)



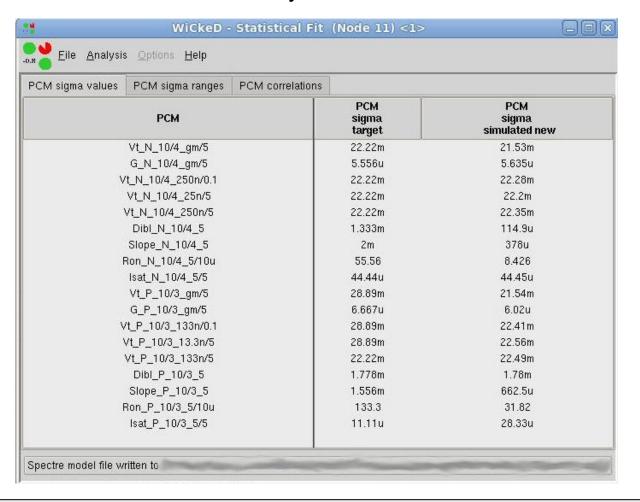
newly created statistics Target

- New result displays
 - Correlation matrix
 - multi-column/row sort
 - rearranging columns/rows manually
 - Delta in correlation matrix
 - Comparison of standard deviation



Comparison of the standard deviations

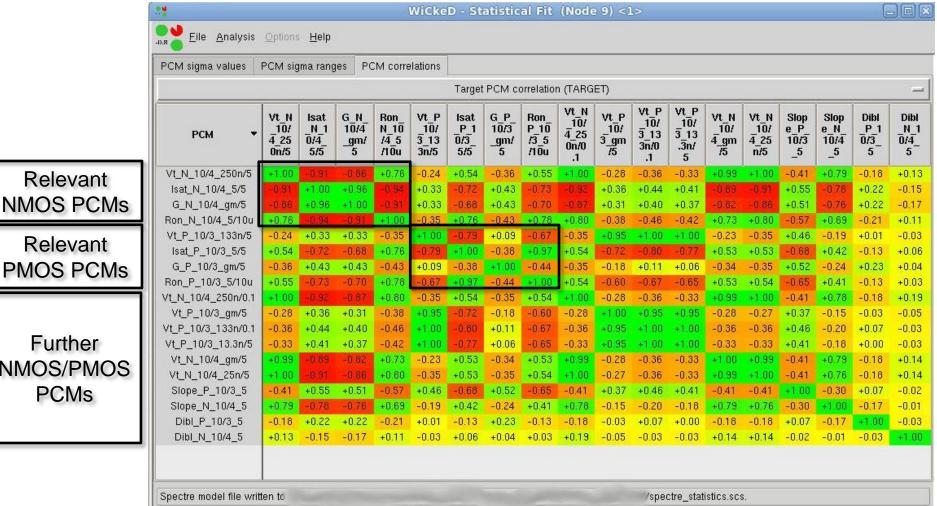
- NMOS and PMOS PCMs of an IC technology
- Standard deviation is matched very well





Target PCM correlations

NMOS and PMOS PCMs of an IC technology



Relevant

Relevant



Comparing the newly created model statistics with the target

NMOS and PMOS PCMs of an IC technology

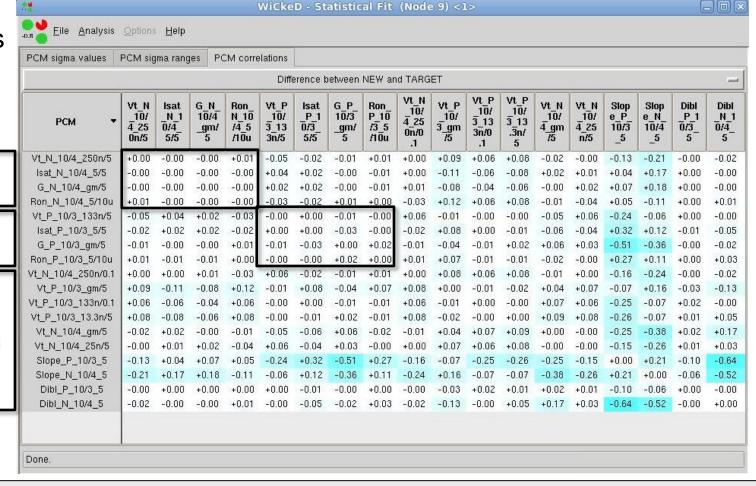


Correlations match very well

Relevant NMOS PCMs

Relevant PMOS PCMs

Further NMOS/PMOS PCMs





Further advances in WiCkeD Statistical Fit

- Input data
 - Further input file formats supported
 - Comments in input files allowed
 - Automatic matching of PCM names of data sets and of spice simulation
- **7** Log
 - Detailed log added
- While operating
 - Progress bar added
 - Improved status messages
 - Extended error handling
 - Improved handling of missing PCM values
- Export of results
 - Export of sigma values and covariance matrixes to Excel format
 - Spice include file with determined correlations



Conclusion

- ✓ Ultimate goal of statistical modeling to reproduce the correlations between measurements of PCMs can be achieved
- Ready to use WiCkeD Statistical Fit solution to determine a correlated statistics
- Removing of mismatch effects from PCM measurements
- Support of different structures of correlation matrixes
- Several input data checks
- Monte Carlo based Validation of results





Thank You!